

FOR IMMEDIATE RELEASE
September 2004

Media Contacts:
Dick Garard, CEO
Lambda Technologies
919-462-1919

Bob Schauer
Director, Sales & Service
Lambda Technologies
bschauer@microcure.com

Lambda Technologies Expands Microwave Product Line and Licenses Extensive IP for Tunable Cavity and Plasma Process Reactor

Lambda Technologies, Inc. announced that it has completed a license agreement with Michigan State University for the exclusive worldwide rights to manufacture and sell MSU's patented microwave material processing technology. The basis of the new technology is a proprietary, tunable single mode reactor with options for a unique plasma disk design that provides both flexibility and inherent scalability to large area applications.

According to Richard S. Garard, President & CEO of Lambda Technologies, "the MSU technology is a perfect complement to our existing Variable Frequency Microwave (VFM) technology product line. To date, we have not pursued material process applications for small volume, precise controlled thermal process requirements, such as heating of fibers and/or curing of various small form factor products. The MSU tunable single mode resonant cavity is ideal for these applications. Furthermore, with VFM, we have not pursued the various microwave plasma applications in the advanced materials market. The initial applications where we will apply this newly acquired technology will be high density / low energy plasma etch and CVD, specifically for diamond film deposition, where significant background with the MSU technology already exists."

Lambda Technologies, Inc. is a capital equipment and process development company specializing in applying proprietary microwave technologies for the processing of advanced materials and other high value added heating applications.